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## Application Information

Title Line One::

Title Line Two::

Total Drawing Sheets::

Docket Number::

POLISHING PAD AND POLISHING METHOD

FOR SEMICONDUCTOR WAFER

109352

## Continuity Information

>This application is a::

Application One:: Filing Date::

371 of

PCT/JP00/05595 August 21, 2000

## Prior Foreign Applications

Foreign Application One::

Filing Date::

11-246243 August 31, 1999

Country::

JAPAN

Priority Claimed::

YES